



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Takeshi KIJIMA et al.

Application No.: 10/724,635

Docket No.: 117926

Filed: December 2, 2003

For: METHOD OF MANUFACTURING OXIDE THIN FILM, METHOD OF
MANUFACTURING FERROELECTRIC THIN FILM, FERROELECTRIC THIN
FILM, FERROELECTRIC MEMORY DEVICE, AND FERROELECTRIC
PIEZOELECTRIC DEVICE

REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records. A Supplemental Application Data Sheet is attached.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Thomas J. Pardini
Registration No. 30,411

JAO:TJP/al

Date: June 28, 2004

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
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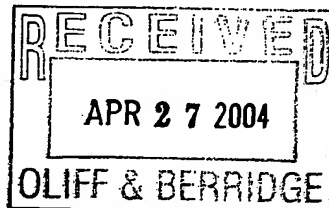


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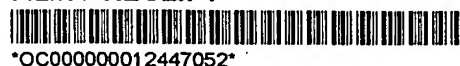
APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/724,635	12/02/2003		1286	117926	14	19	9

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 OLIFF & BERRIDGE, PLC
 P.O. BOX 19928
 ALEXANDRIA, VA 22320



CONFIRMATION NO. 2007

FILING RECEIPT



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Date Mailed: 04/26/2004

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Matsumoto - Shi

Takeshi Kijima, ~~Suwa-shi~~, JAPAN;
 Eiji Natori, ~~Suwa-shi~~, JAPAN;

Chino - Shi

Assignment For Published Patent Application

SEIKO EPSON CORPORATION, Tokyo, JAPAN;

Domestic Priority data as claimed by applicant

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JAPAN 2002-349818 12/02/2002

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Projected Publication Date: To Be Determined - pending completion of Missing Parts

Non-Publication Request: No

Early Publication Request: No

Title

~~Method of fabricating oxide film, ferroelectric film and method of the same, ferroelectric memory device and piezoelectric device.~~
 METHOD OF MANUFACTURING OXIDE THIN FILM, METHOD OF
 MANUFACTURING FERROELECTRIC THIN FILM, FERROELECTRIC
 THIN FILM, FERROELECTRIC MEMORY DEVICE, AND
 FERROELECTRIC PIEZOELECTRIC DEVICE